

CLEAN COPY OF THE CURRENT/PENDING CLAIMS

13. (Amended) A method for coupling an IC to a supporting surface comprising:
- providing an IC;
 - providing a supporting surface to which the IC is to be mechanically and electrically bonded;
 - providing a pre-form assembly comprising a base layer and a sacrificial layer, the base layer comprising wire or solder paste through conductors, or the base layer comprising a fiber mesh material impregnated with a thermoset;
 - applying the pre-form assembly to either the IC or supporting surface;
 - peeling away the sacrificial layer;
 - sandwiching the base layer between the IC and the supporting surface; and
 - curing the base layer.
14. The method of claim 13 wherein providing the preform assembly comprises:
- providing a sacrificial layer;
 - coating the sacrificial later with a release coating;
 - applying a thermosetting material on top of the release coating;
 - curing the thermosetting material to form a B-stage layer; and
 - inserting through conductors into the thermosetting material.
15. The method of claim 14 wherein the step of inserting through conductors into the thermosetting material comprises either piercing wires into the thermosetting material, or lasing or drilling and subsequently filling holes in the thermosetting material with a solder paste.

- A 2
SUB B2
22. (Added) The method of claim 14 wherein the release coating at least partially comprises silicon, Teflon[®], or graphite release agents.
23. (Added) The method of claim 13 wherein the base layer comprises a fine mesh fiber material impregnated with a thermoset, and the fine mesh fiber is thermally conductive.
24. (Added) The method of claim 13 wherein the base layer comprises a fine mesh fiber material impregnated with a thermoset and the fine mesh fiber is electrically non-conductive.
25. (Added) The method of claim 13 wherein the base layer comprises a thermoset intermixed with a particle filler.
26. (Added) The method of claim 25 wherein the particle filler is thermally conductive.
27. (Added) The method of claim 25 wherein the particle filler is electrically non-conductive.